

For: Our New U.S. Patent Application. Our Ref: 7270
[SEMICONDUCTOR DEVICE AND ITS FABRICATION METHOD]
(K. TORII; et al)

LIST OF THE PRIOR ART REFERENCES CITED IN THE SPECIFICATION

1. Japanese Laid-Open No.5-090606. (Cited on page 1, line 26)
 2. Japanese Laid-Open No.2-288368. (Cited on page 2, line 11)
 3. Japanese Laid-Open No.3-256358. (Cited on page 2, line 16)
 4. Japanese Laid-Open No.7-014993. (Cited on page 2, line 24)
 5. Japanese Laid-Open No.7-169854. (Cited on page 3, line 6)
-